

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Shinya TAKYU et al.)
Application No.: Not Yet Assigned) Group Art Unit: Not assigned
Filed: April 2, 2004) Examiner: Not assigned
For: MANUFACTURING METHOD)
OF SEMICONDUCTOR)
DEVICE)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)

Pursuant to 37 C.F.R. §§1.56 and 1.97(b), applicants bring to the Examiner's attention the documents listed on attached Form PTO-1449. Except for the listed U.S. patents, copies of the listed documents are attached. Applicants respectfully request that the Examiner consider the documents listed on attached Form PTO-1449 and indicate that they were considered by making an appropriate notation on this form.

This Information Disclosure Statement is being filed with the above-referenced application.

The following is a concise statement of relevance of the non-English language documents:

1. Japanese Patent Application No. 2000-91281 - discloses a peeling way of surface protection film (Fig. 4, page 2, lines 60-73).

2. Japanese Patent Application No. 2000-315697 - discloses a vacuum adsorption way and a peeling way of surface protection film (Fig. 10, page 11, lines 23-44).

3. Japanese Patent Application No. 2003-179126 - (which corresponds to U.S. Application Serial No. 10/254,982) discloses a vacuum adsorption way and the peeling way of surface protection film (Page 17, Figs. 4-7).

An English language abstract of each of the listed documents is enclosed.

This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that each or all of the listed documents are material or constitute "prior art." If the Examiner applies any of the documents as prior art against any claim in the application and applicants determine that the cited documents do not constitute "prior art" under United States law, applicants reserve the right to present to the Office the relevant facts and law regarding the appropriate status of such documents. Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed documents, should one or more of the documents be applied against the claims of the present application.

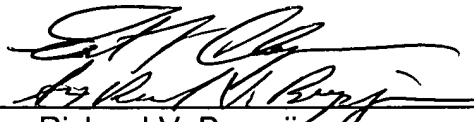
If there is any fee due in connection with the filing of this Statement, please

charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: April 2, 2004

By: 
Richard V. Burguijén
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Enclosures
RVB/FPD/dvg

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INFORMATION DISCLOSURE CITATION

Atty. Docket No. 02887.0274	Application No.
Applicant Shinya TAKYU et al.	
Filing Date April 2, 2004	Group: Not assigned

U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
	4,778,326	10/18/88	Althouse et al.			
	4,556,362	12/3/85	Bahnck et al.			
	4,667,944	5/26/87	Althouse			
	6,220,771	4/24/01	Tung et al.			
	6,209,532 B1	4/3/01	Arnold et al.			

FOREIGN PATENT DOCUMENTS

Document Number	Publication Date	Country	Class	Sub Class	Translation Yes or No
2000-091281	3/31/00	Japan			Abstract
2000-315697	11/14/00	Japan			Abstract
2003-179126	6/27/03	Japan			Abstract

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Tetsuya KUROSAWA et al., "Method Of And Mechanism For Peeling Adhesive Tape Bonded To Segmented Semiconductor Wafer", Serial No. 10/254,982, Filed: September 26, 2002.

Examiner	Date Considered
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	
Form PTO 1449	Patent and Trademark Office - U.S. Department of Commerce